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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Thomas A. Figura, Kevin Donohoe, & Thomas Dunbar

Serial No.:

Filed: December 22, 1999

Title: USE OF A PLASMA SOURCE TO FORM A LAYER DURING THE FORMATION OF A SEMICONDUCTOR DEVICE

Group Art Unit:

§

§ § § Application Examiner:

Atty. Docket: 94-0280.04

4/2 3-2-00 Links B.

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents Washington, D.C. 20231

Dear Sir:

"EXPRESS MAIL" MAILING LABEL NO. EL003001606

DATE OF DEPOSIT: 3-29

I HEREBY CERTIFY THAT THIS PAPER IS BEING DEPOSITED WITH THE UNITED STATES POSTAL SERVICE "EXPRESS MAIL POST-OFFICE TO ADDRESSEE" SERVICE UNDER 37 C F R § 1.10 ON THE DATE INDICATED ABOVE AND IS ADDRESSED TO THE ASSISTANT COMMISSIONER FOR PATENTS, WASHINGTON, D.C. 20231.

Signature

After awarding this application the benefit of the filing date of the great-grandparent application, filed June 2, 1995, please amend the accompanying continuation application as follows:

IN THE SPECIFICATION

After the title, please include the following --

RELATED APPLICATIONS

This application is a divisional of a pending U.S. application, serial number 09/046,835, filed on October 24, 1997; which is a continuation of U.S. application serial number 08/787,453, filed January 22, 1997 and issued on September 7, 1999 as U.S. Patent No. 5,950,092; which is a continuation of U.S. application Serial Number 08/458,861, filed June 2, 1995 and now abandoned. --